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Semiconductor devices – Micro-electromechanical devices – Part 48: Test method for determining solution concentration by optical absorption using MEMS fluidic device

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Part 48: Test method for determining solution concentration by optical absorption using MEMS fluidic device

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The text of this International Standard is based on the following documents:

Draft	Report on voting
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Full information on the voting for its approval can be found in the report on voting indicated in the above table.

The language used for the development of this International Standard is English.

This document was drafted in accordance with ISO/IEC Directives, Part 2, and developed in accordance with ISO/IEC Directives, Part 1 and ISO/IEC Directives, IEC Supplement, available at www.iec.ch/members_experts/refdocs. The main document types developed by IEC are described in greater detail at www.iec.ch/publications.

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The committee has decided that the contents of this document will remain unchanged until the stability date indicated on the IEC website under webstore.iec.ch in the data related to the specific document. At this date, the document will be

- reconfirmed,
- withdrawn, or
- revised.

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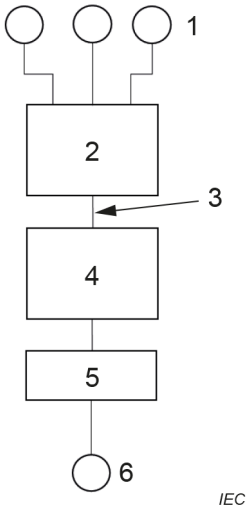
INTRODUCTION

A MEMS fluidic device is one of the key devices in MEMS technologies, including bio-MEMS, chemical MEMS, and micro TAS (total analytical system). A MEMS fluidic device, in general, consists of several micro components such as inlet ports for injection of a filtered sample and reagents to induce a sample to have the optical absorption at specific wavelength, a microfluidic mixer for physical mixing, a micro-reactor for chemical or biological reaction, a detection area for determining the concentration of solution using optical source and detector from the outside, as well as outlet ports for waste-out as shown in Figure 1. All components in a MEMS fluidic device are connected with microfluidic channels. In case there is a synthesizing solution with absorption at a specific wavelength in a MEMS fluidic device, it is possible to determine the concentration by using an absorption method at specific absorption wavelength based on the Beer-Lambert law [1][1]. MEMS fluidic devices are more cost-effective than conventional analysis tools and methods since expensive reagents and human power are used less and in-situ monitoring is enabled.



Key

1 inlet ports

2 microfluidic mixer

3 microfluidic channel

4 micro-reactor

5 detection area

6 outlet port

Figure 1 – Schematic drawing of micro components in a MEMS fluidic device (top view)

[1] Numbers in square brackets refer to the Bibliography.

SEMICONDUCTOR DEVICES – MICRO-ELECTROMECHANICAL DEVICES –

Part 48: Test method for determining solution concentration by optical absorption using MEMS fluidic device

1 Scope

This part of IEC 62047 specifies the requirements and testing method to determine the solution concentration by optical absorption using MEMS fluidic device.

2 Normative references

There are no normative references in this document.